

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) TWI-12410	Application Number NEW
	Applicant(s) Craig Uhrich et al.	
	Filing Date HEREWITH	Group Art Unit

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
MS	AA	5,608,526	03/04/1997	Piwonka-Corle et al.	356	369	01/19/1995
MS	AB	5,877,859	03/02/1999	Aspnes et al.	356	364	07/24/1996

FOREIGN PATENT DOCUMENTS

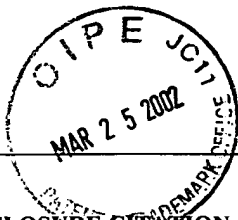
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
MS	AC	WO 99/02970	01/21/1999	PCT	G01N	21/21		

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

MS	AD	D.E. Aspnes & A.A. Studna, "High Precision Scanning Ellipsometer," <i>Applied Optics</i> , Vol. 14, No. 1, January 1975, pp. 220-228.

Examiner <i>David G. Hogan</i>	Date Considered <i>9/7/99</i>
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	



INFORMATION DISCLOSURE CITATION
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Docket Number (Optional)

I-12410

Application Number

09/848,733

Applicant(s)

Craig Uhrich et al.

Filing Date

May 3, 2001

Group Art Unit

2877

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
DP	BA	3,486,805	12/30/1969	Kobayashi	350	2	02/09/1966
DP	BB	5,121,255	06/09/1992	Hayashi	359	656	06/19/1989

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO

OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

Examiner

[Signature]

Date Considered

9/17/03

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